

Inventor: William H. Howland  
 "APPARATUS FOR DETERMINING DOPING CONCENTRATION OF A SEMICONDUCTOR  
 WAFER"

Attorney Docket No.: 1880-031286

Application No.: 10/616,641



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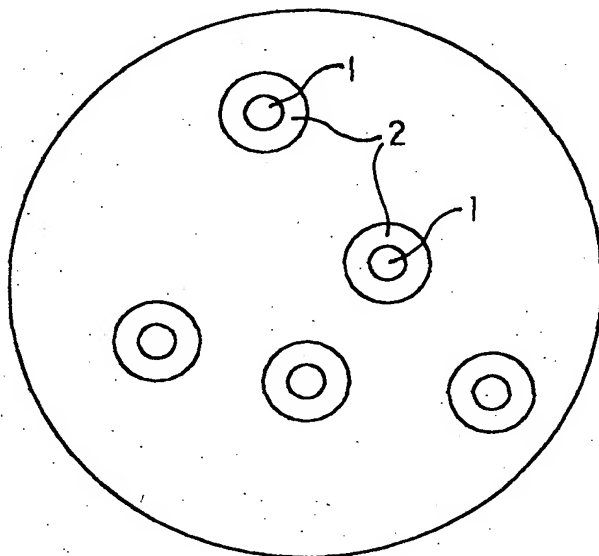


FIG. 1  
 (PRIOR ART)

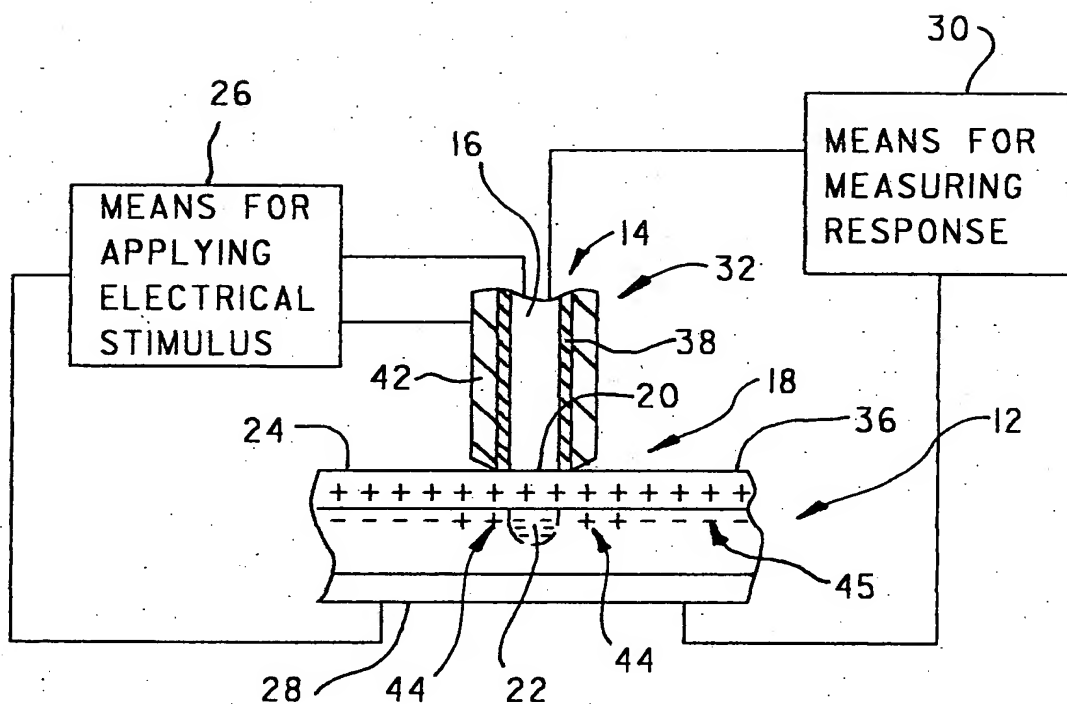


FIG. 4

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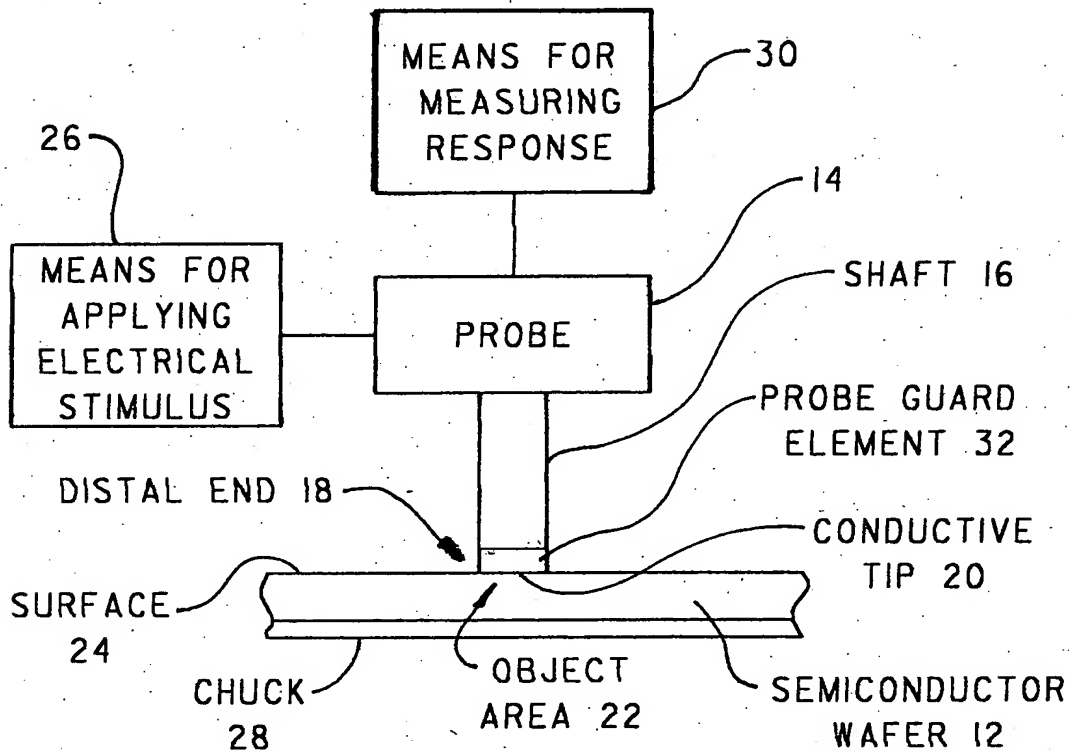


FIG. 2

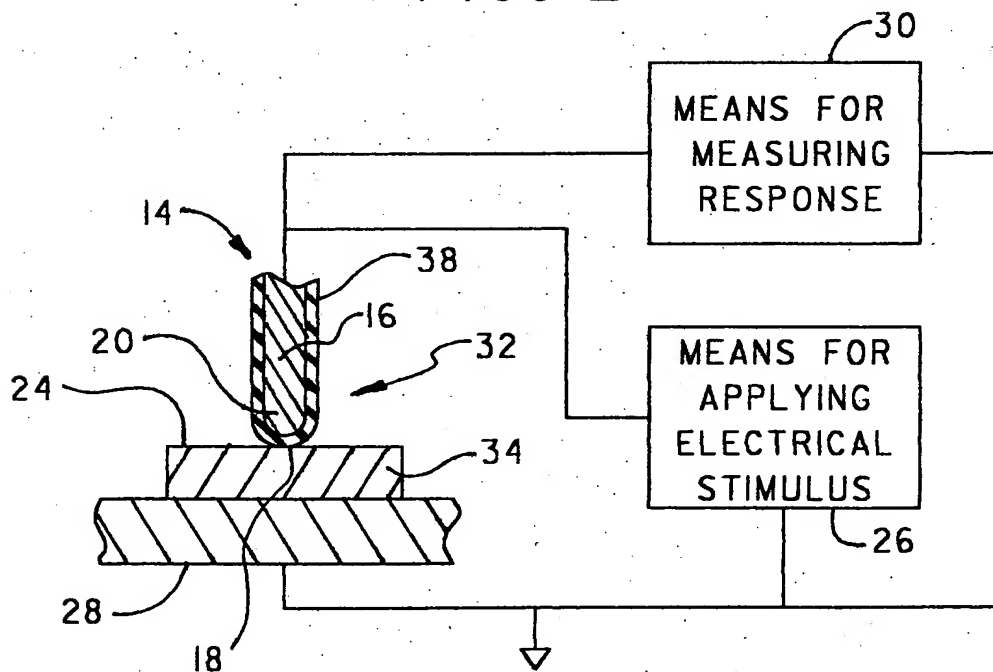
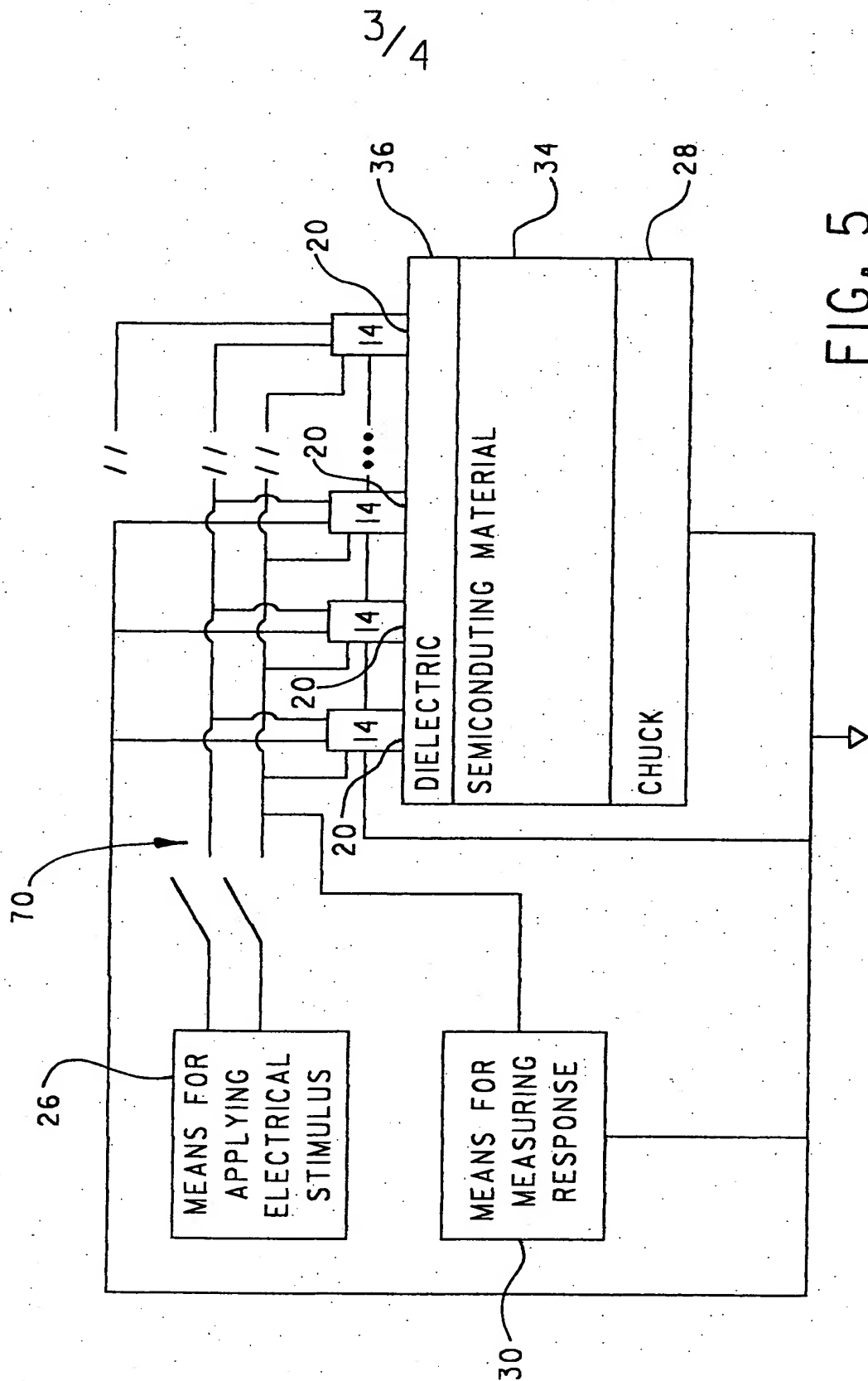


FIG. 3



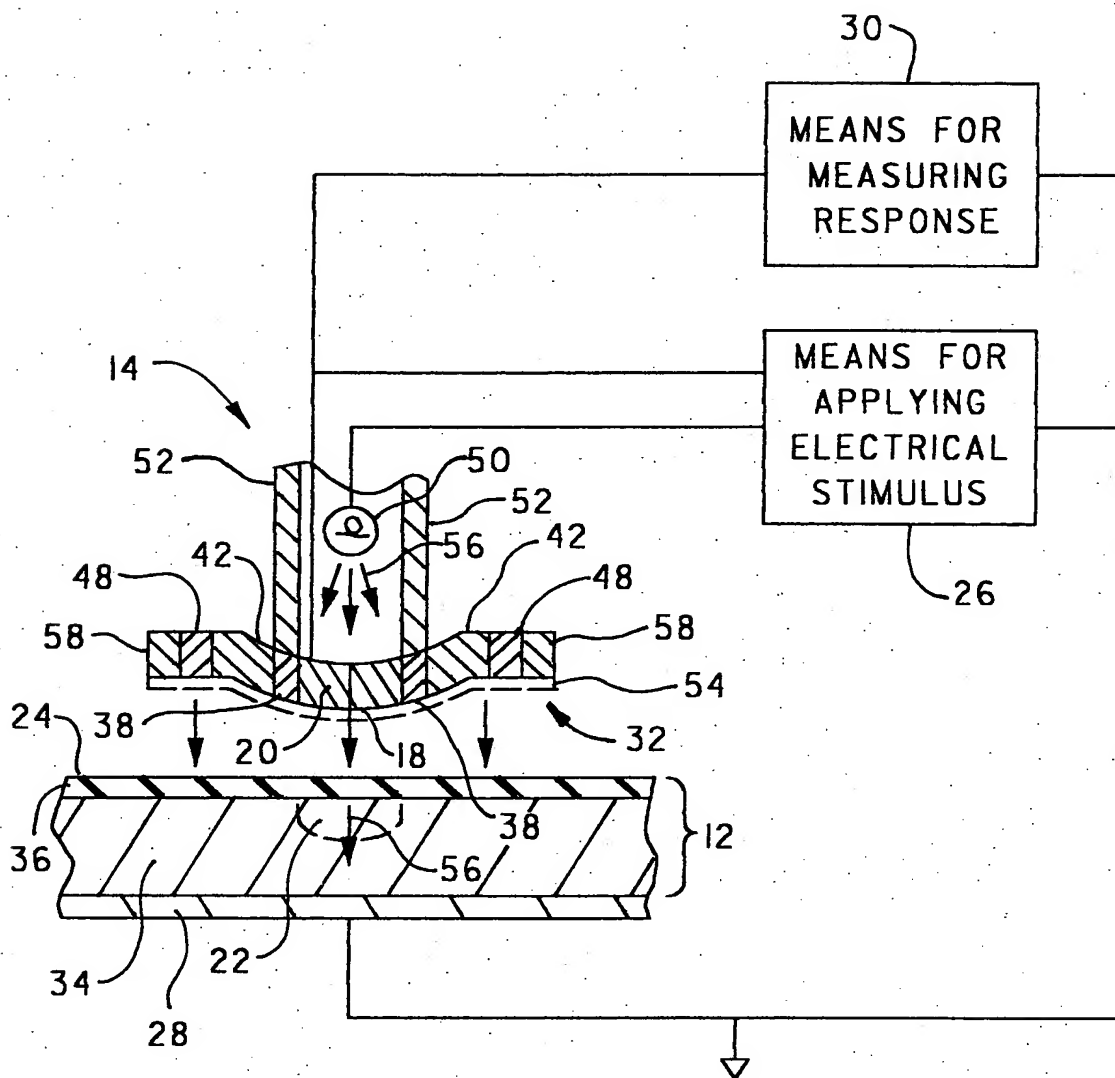


FIG. 6